

Laboratory Infrastructure for Instrumentation Development: A whirlwind tour

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With contributions from M. Demarteau (Argonne), G. Gilchriese (LBNL), D. Lissauer (BNL), E. Ramberg (Fermilab), & G. Haller (SLAC); apologies to LANL, LLNL, PNNL



Facilities at Argonne

- Atomic Layer Deposition Reactor
 - » MCP functionalization for LAPPD
- Plasma enhanced Atomic Layer Deposition System
- Large Assembly Facilities
- Photocathode Growth Facility



Beneq ALD reactor



Large construction facility

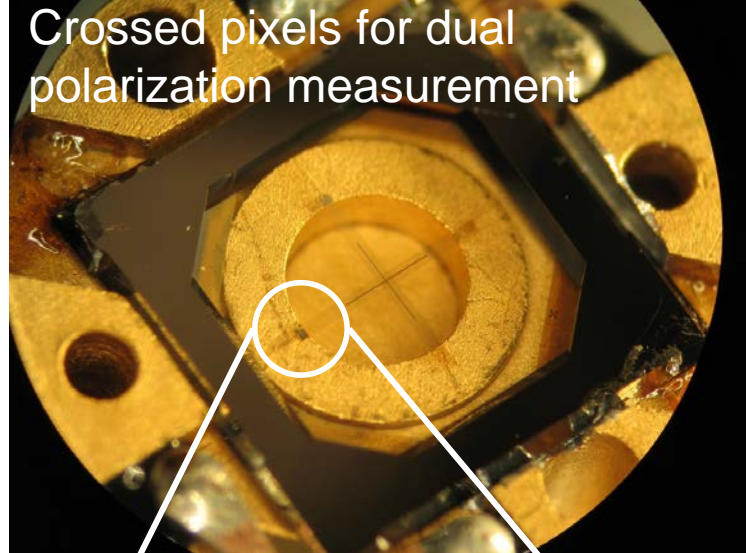


Photocathode growth

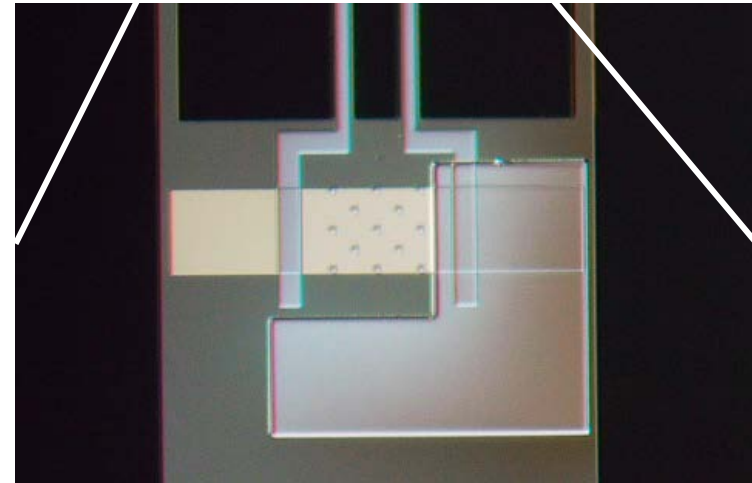
Superconducting Thin Film Deposition



Materials Science Deposition System for superconducting detectors

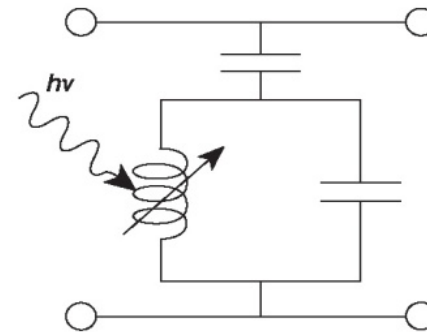


- Using thin film deposition techniques, develop Transition Edge Sensors from scratch
- Engineer superconducting structures to shape the R-V relation
 - » $8 \mu\text{m} \times 1186 \mu\text{m}$ PdAu dipole on $200 \mu\text{m} \times 2100 \mu\text{m}$ SiN
- Magnetic materials to regulate the thermal bandwidth

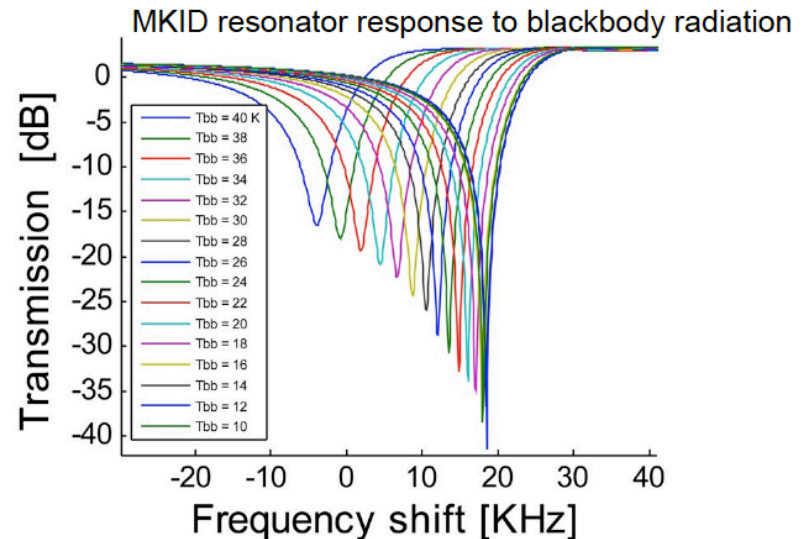


Microwave Kinetic Inductance Detector Fabrication

- Next generation more sensitive CMB detectors: MKIDs
- Superconducting resonator-based photon detectors
 - » Sub-millimeter to X-ray detection
 - » Each pixel at different resonant frequency
 - » Potentially simple multiplexing
- Measure incident power (pW) by change in resonator frequency and quality factor (Q)

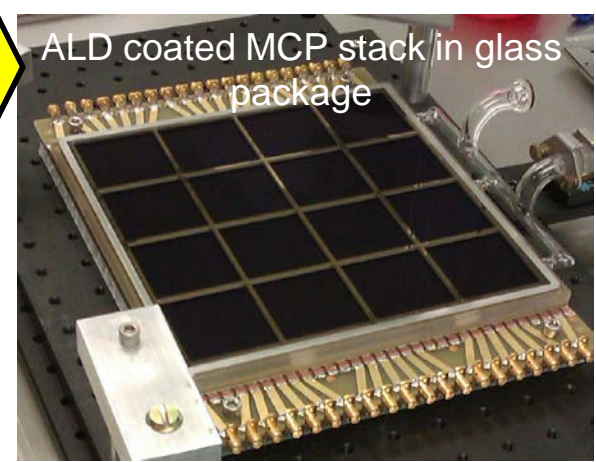
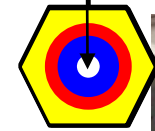
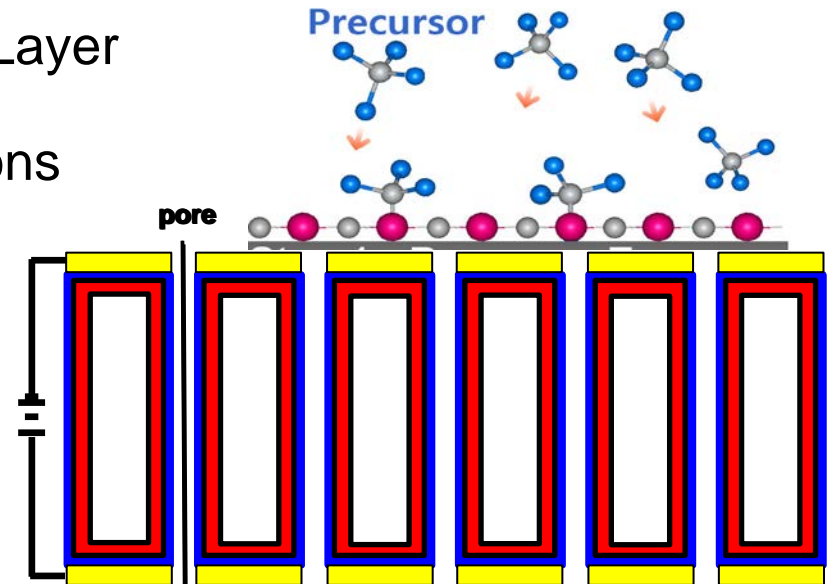
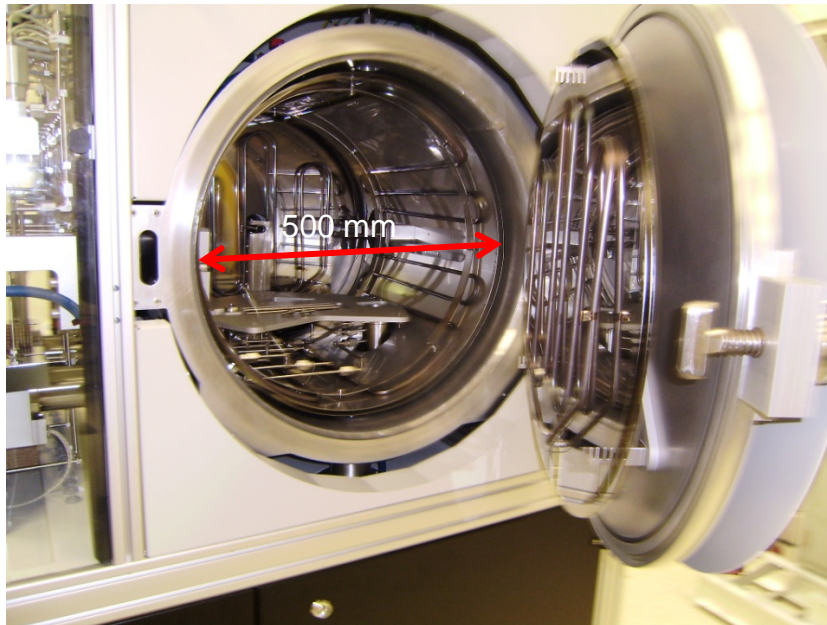


MKID - Microwave Kinetic Inductance Detector



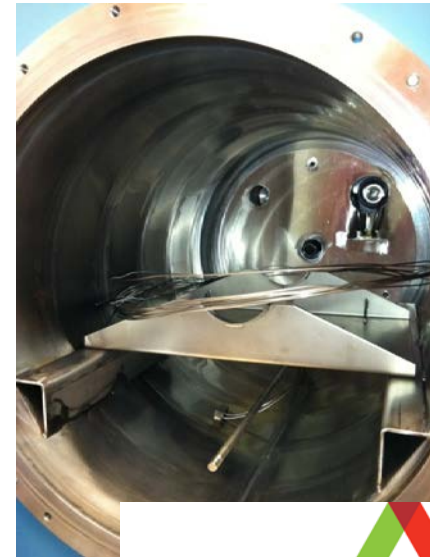
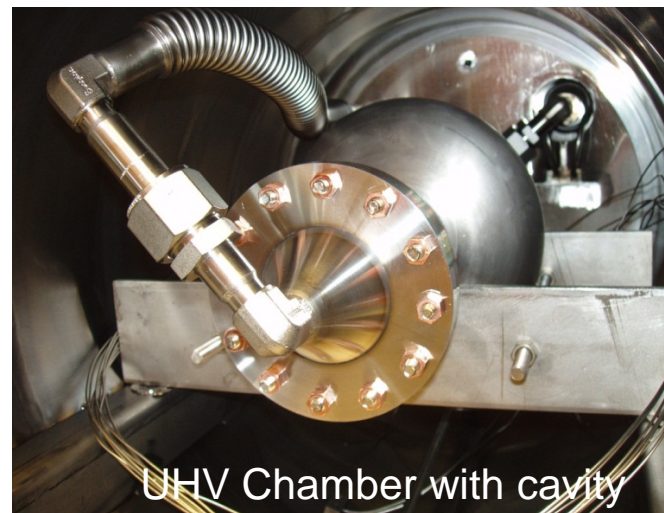
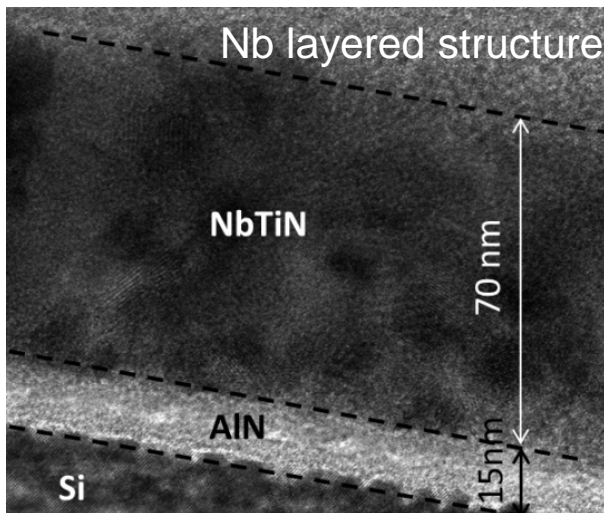
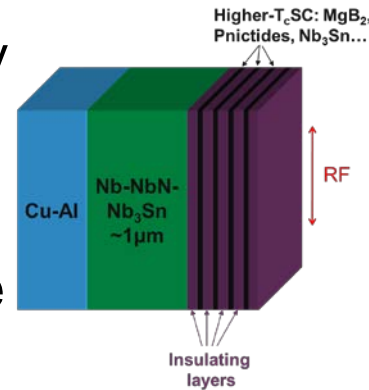
Atomic Layer Deposition Facilities

- Many reactors available for Atomic Layer Deposition
- Alternating surface/molecule reactions
 - » MOCVD: partly gas phase rxns
 - » PVD preformed pieces + surface reassembly
- Deposition of single atomic layers



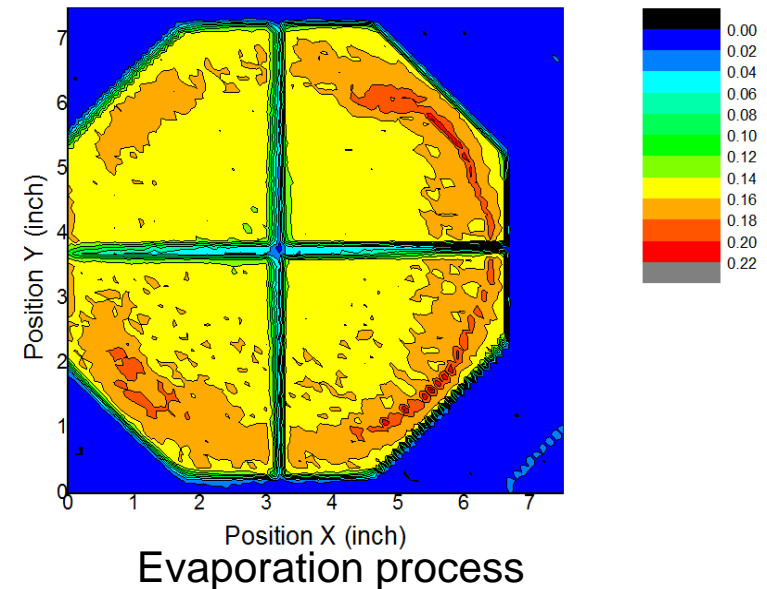
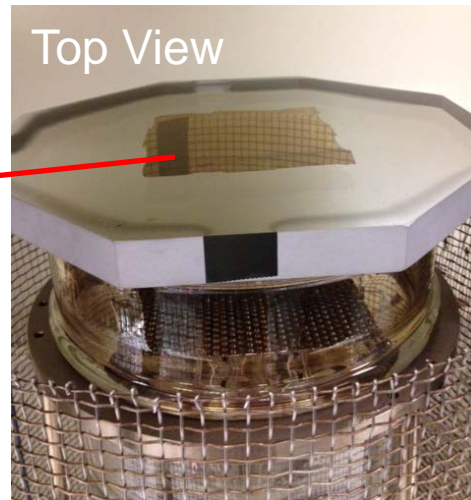
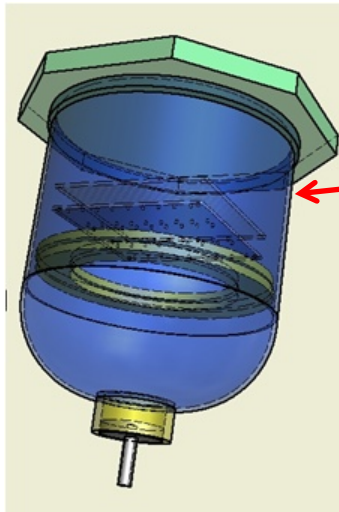
Superconductor Cavities through ALD

- Able to synthesize better superconductors than Niobium:
 - » NbTiN with new ALD chemistry is very pure (<0.05%)
 - » NbTiN $T_c = 14\text{K}$ for 60 nm thick film (bulk=16K)
- Multilayer structure: Aluminum Nitride (AlN) + NbTiN works perfectly: (15 nm AlN/ 70 nm NbTiN) x n



Photocathode Growth Facility

- Facilities for small and large area bi-alkali photocathodes



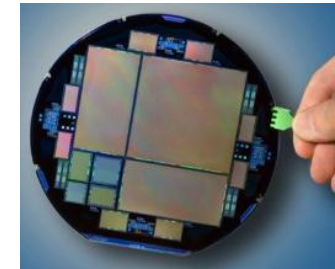
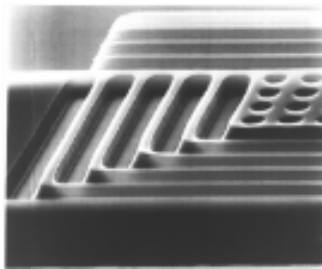
- In the process of developing facility for production fabrication of large-area, planar, cost-effective photodetectors

Facilities at LBNL

- Physics Division operates or established three unique facilities:
 - » Micro Systems Lab (MSL) – established and operates
 - » LBNL IC design group – established
 - » LBNL Composites Facility – established
- A large number of other facilities are operated by the LBNL Engineering Division, other divisions, or UC Berkeley
- Physics Division also maintains critical in-house capabilities (e.g. silicon detector assembly, clean rooms, etc.)
- Equipment in all facilities is important and often valuable
- But the expertise of the personnel is invaluable- takes years of projects and R&D to build up capability

Micro-Systems Lab (MSL)

- Core team: 3 expert engineers and 5 expert technicians
- Design + 700 ft² of class 10 area with full line processing- lithography, thermal processing, thin films, CVD, fry etching, etc.



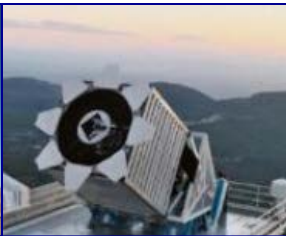
Lithography

Thermal processing

4k x 4k BigBOSS demo

- Plus packaging development, testing & characterization in separate spaces (not shown)

Powered by MSL CCDs:



CTIO/Blanco 4m DEcam, COSMOS
SDSS 2.5m BOSS

Keck 10m LRIS

Mt Hamilton Lick- Echelle

Palomar 200" SWIFT

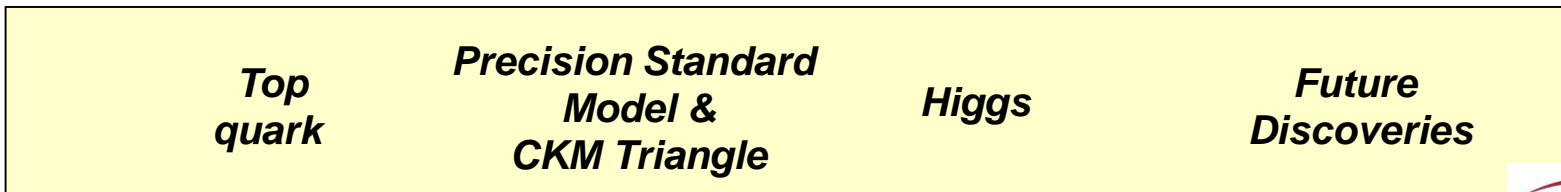
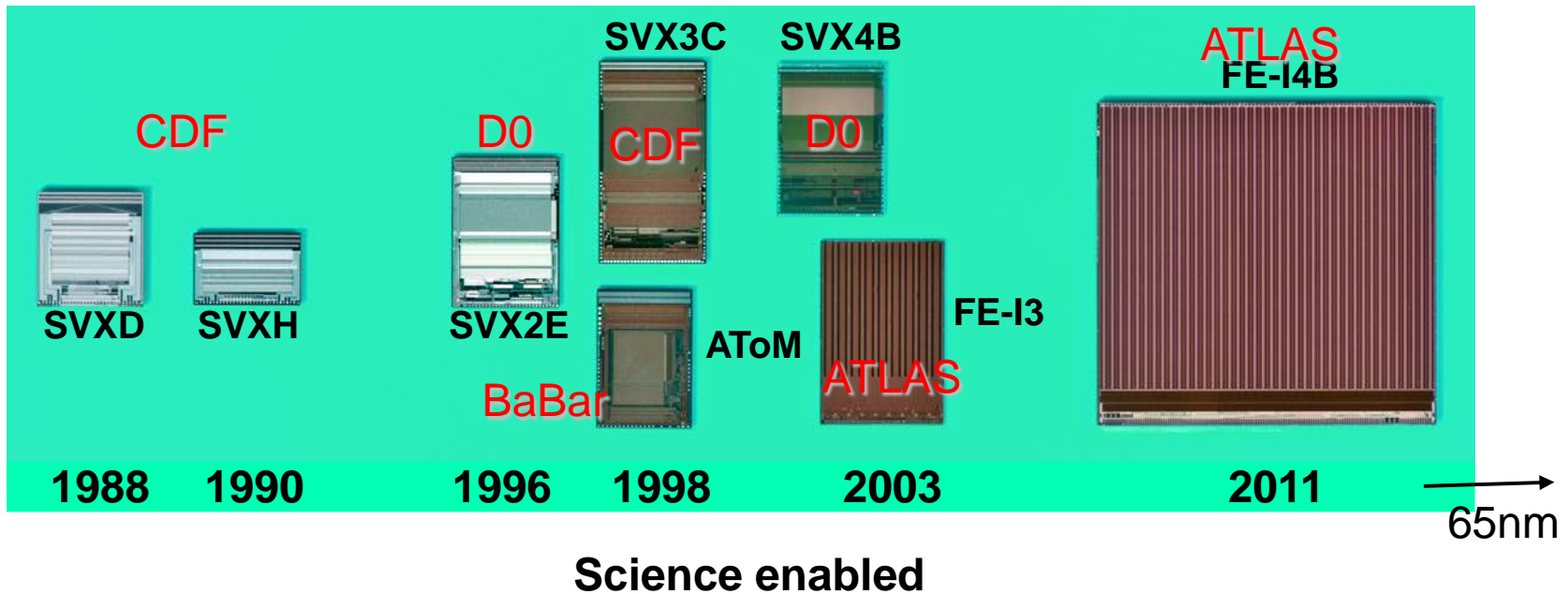
Kitt/ Mayall 4m Mars, RC, KOSMOS

Mt. Hopkins 6.5m

IC Design Group

Core team: 5 IC design engineers

Example of Integrated Circuits for collider vertex detectors



Composites Facility: R&D developments 2008-2012

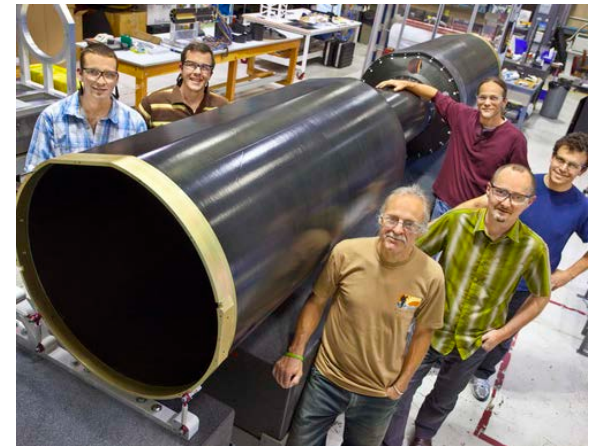
Core team: 3 expert engineers and 3 expert technicians



ATLAS pixels, 2006

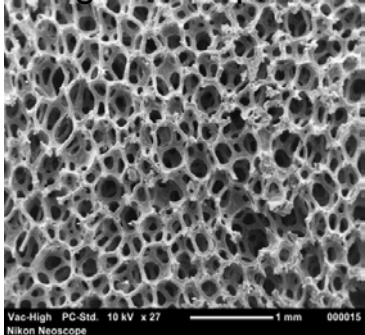


Autoclave



STAR and Phenix Upgrades, 2012

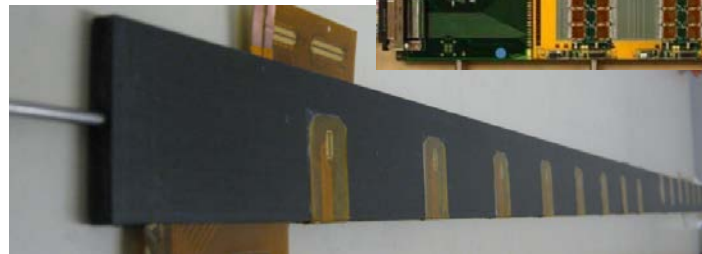
Through Allcomp, Inc SBIR



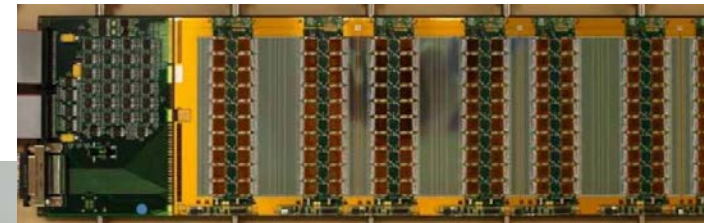
Thermally Conductive
Carbon foam



I-Beam stave



Pixel and strip integrated structures, co-curing



Other available Facilities at LBNL

- Most LBNL and UC Berkeley facilities are available for use as needed, but are too numerous for a complete listing
- Some of the facilities used in Physics Division activities in recent years include:
 - » 88" Cyclotron for proton and ions irradiation
 - » Advanced Light Source electron storage ring
 - » Eng. Div. mechanical design, fabrication and metrology
 - » Eng. Div. electronic design and assembly
 - » Eng. Div. class 100 assembly clean room
 - » Molecular Foundry nanofabrication facility
 - » Earth Sciences Div. ICP mass spectrometer
 - » Radiation Protection group and Low Background Counting facilities
 - » Eng. Div. Molecular Beam Epitaxy facility
 - » National Center for Electron Microscopy
 - » National Energy Research Scientific Computing Center (NERSC)
 - » UC Berkeley Nanolab

Physics Division in-House Capabilities

- Beyond the LBNL Engineering Division, the Physics Division maintains local capabilities used heavily for HEP detector work
 - » 2 automatic wire bonders and associated preparation and QC equipment (only such facility at LBNL)
 - » 3 coordinate measurement machines
 - » Class 1000 ESD safe assembly clean room
 - » Small machine shop
 - » Electronic assembly and test space and equipment
 - » Support for various R&D lab spaces, gasses, vents, vacuum, etc.
 - » Electron microscope



Facilities at Brookhaven

- Design and fabrication of noble element detectors – gas- and liquid-based, for photons, charged particles and neutrons.
- Semiconductor detectors for photons, charged particles- silicon, diamond
- Advanced Microelectronics for a wide range of sensor applications: low-noise ASIC R&D and ASIC design with CADENCE software as major tool
- Multiple Clean Rooms
- Printed Circuit Board Design, Fabrication and Assembly, including component assembly, ball grid arrays and X-ray diagnostics
- Wire Bonding and Bump Bonding for high channel count systems
- Photo-Cathode Research
- Gamma/Neutron Sources for Radiation Effects Studies

Summary Descriptions of BNL Infrastructure

- Noble Element Detectors
 - » Unique expertise in detector simulation and design for fiducial volumes of one kton and more
 - » Development of new gas detector concepts, using sealed radioactive sources, energized X-ray sources, and synchrotron beam lines
- Semiconductor Detectors
 - » Fully equipped semiconductor detector development and processing laboratory, supporting detector and JFET technology in 4" and 6" high resistivity silicon wafers
 - » New capabilities for design and fabrication of diamond detectors for synchrotron beam position and intensity measurement

Summary Descriptions of BNL Infrastructure

- Advanced Microelectronics
 - » Expertise in low-noise ASIC system level design, transistor level design, mask layout, fabrication and testing
 - » Cold electronics designs for MicroBooNE & LBNE ($\sim 90^\circ$ K)
- Clean Rooms
 - » 550 ft² class 100 clean room dedicated solely to silicon processing, primarily 4" and 6" high resistivity wafers
 - » Equipped with oxidation, lithography, developing, metallization, inspection and measuring systems
 - » 350 ft² class 1,000 clean room for fabrication, inspection and assembly of gas-based detectors and systems requiring particulate-free environment

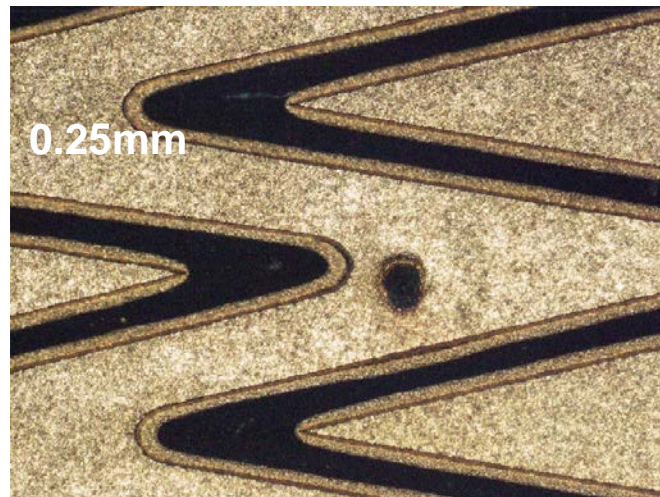
Summary Descriptions of BNL Infrastructure

- Printed Circuit Board Design, Fabrication and Assembly
 - » Personnel, software and equipment supporting production of high-precision multi-layer circuit boards
 - » Mentor Graphics software and laser photo-plotting
 - » Fabrication capabilities include multilayer boards (up to 12), rigid-flex boards, optical inspection of individual layers, computer-controlled drilling and routing
- Wire Bonding and Bump Bonding
 - » Manual and automatic machines for wire bonding pixels or strips on silicon/diamond detectors to respective inputs on circuit boards containing ASICs
 - » New techniques being developed for bump bonding of small-pixel sensors to ASICs

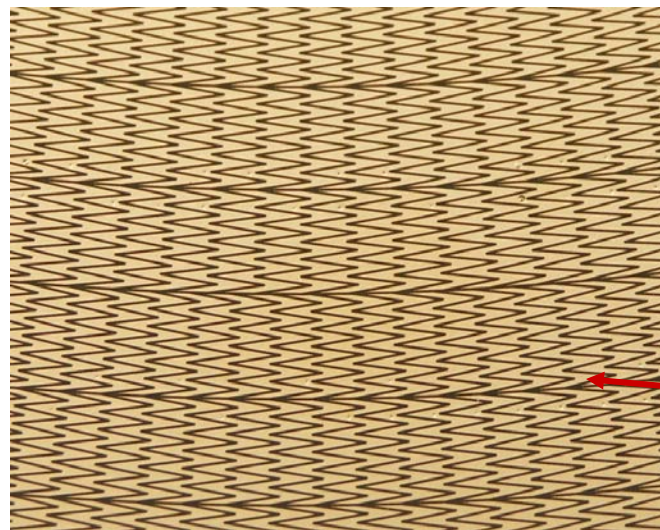
Summary Descriptions of BNL Infrastructure

- Photo-Cathode Research
 - » Electron transport characteristic measurements LAr, using photoemission from gold photocathode immersed in LAr excited by fast laser pulse
 - » Broader program of photo-cathode studies using antimony, multi-alkali photocathode coatings for photo-injectors that also contributes to better understanding of properties and photo-efficiency of conventional photocathodes.
- Gamma/Neutron Sources
 - » Radiation effects facility containing 5kCi ^{60}Co source, 3mCi thermal neutron source, and 14 MeV energized neutron source.

Example of Anode Pad /ASIC Board for Gas TPC



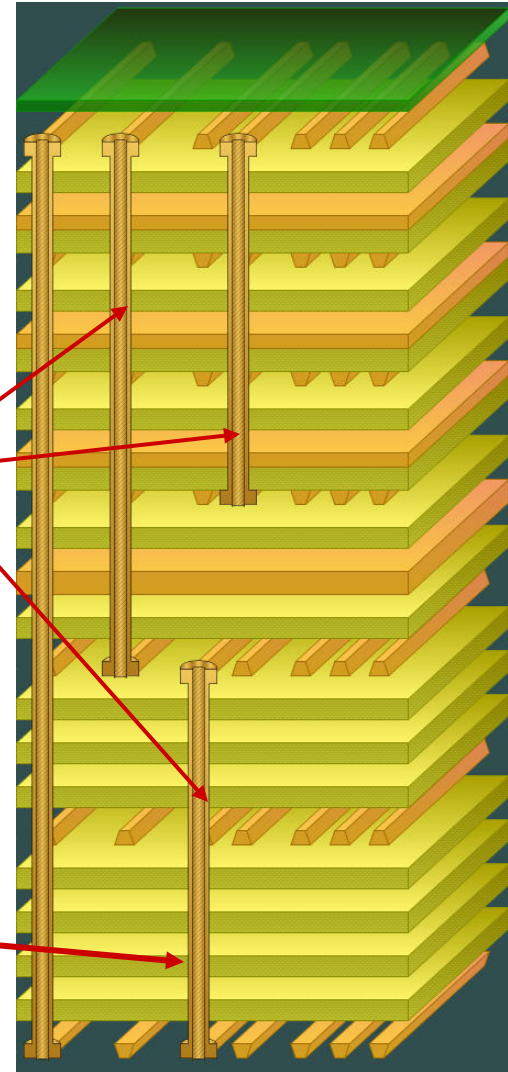
Close-up of zig-zag pads



Zig-zag pads

0.1mm

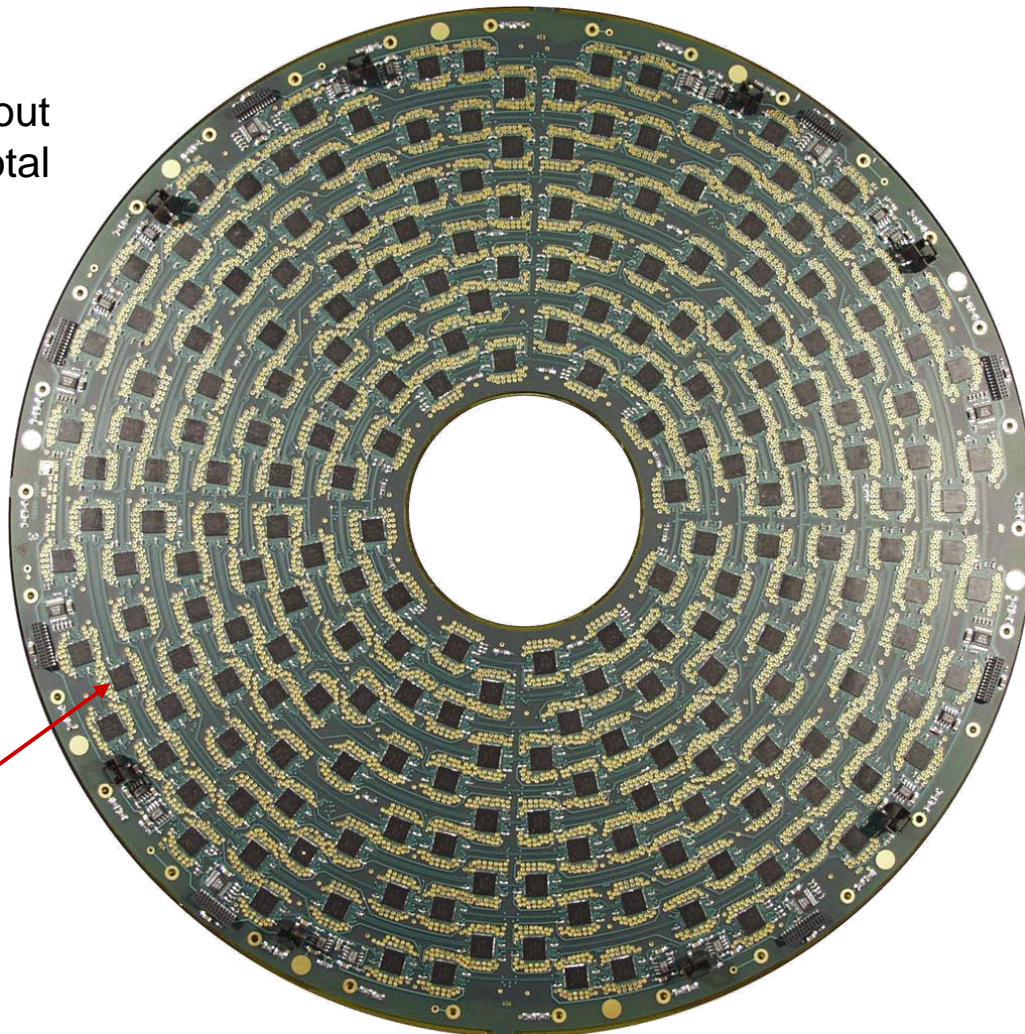
Blind Vias



Example of Anode Pad /ASIC Board for Gas TPC

Rear of board: about 8000 channels total

32-channel ASIC



35 cm

Facilities at Fermilab

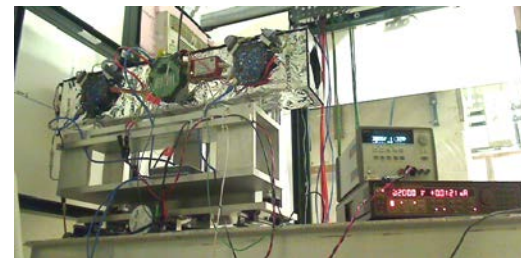
- Wide array of research capabilities:
 - » Test beam facility
 - » Silicon Detector facility
 - » Liquid argon test facility
 - » NICADD scintillator extrusion facility
 - » CCD characterization facility
 - » Thin-Film Facility
 - » High power laser laboratory
- Experienced, well established engineering groups, such as
 - » ASIC Development
 - » Cryogenics Engineering
 - » Data Acquisition



Scintillator extrusion at Lab 5



Clean rooms and metrology at SiDet



Pixel detector at test beam

Fermilab Silicon Detector Facility



CCD Testing Infrastructure



Wire bonding capability



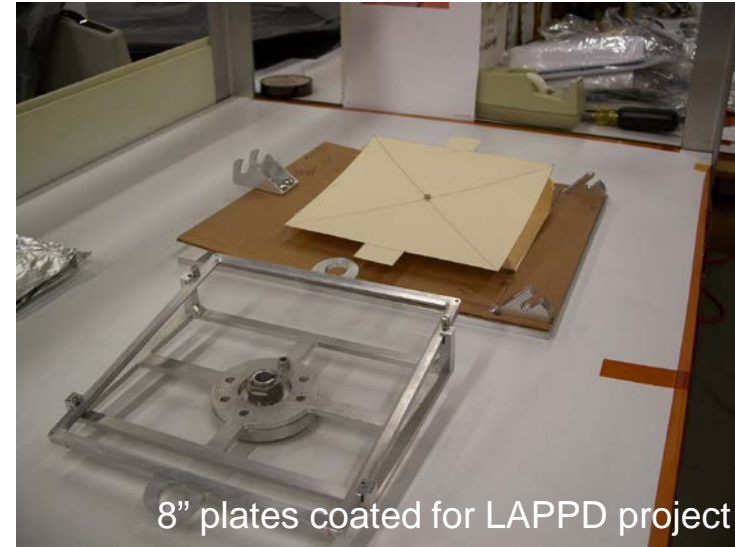
5000 ft² of class 10,000 clean rooms



Metrology and probe stations

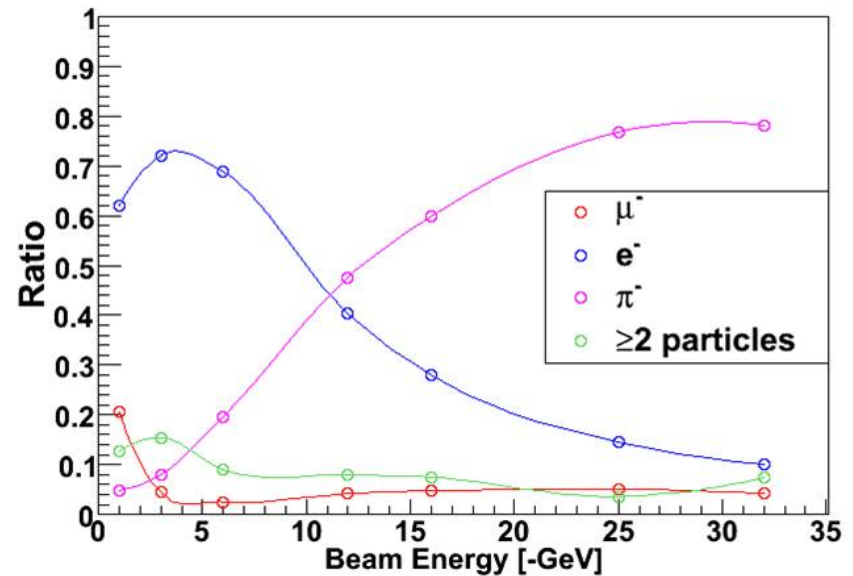
Vacuum Deposition and Thin Film Coatings

- Facility in Lab 7 Run by Eileen Hahn
- High demand from outside Fermilab
- Vacuum deposited thin films of precise thickness from sputtering or evaporation.
- Film thickness as small as 10 \AA to 2 micron or thicker.
- Other capabilities include fiber polishing and splicing, plasma etch cleaning and vacuum baking and annealing



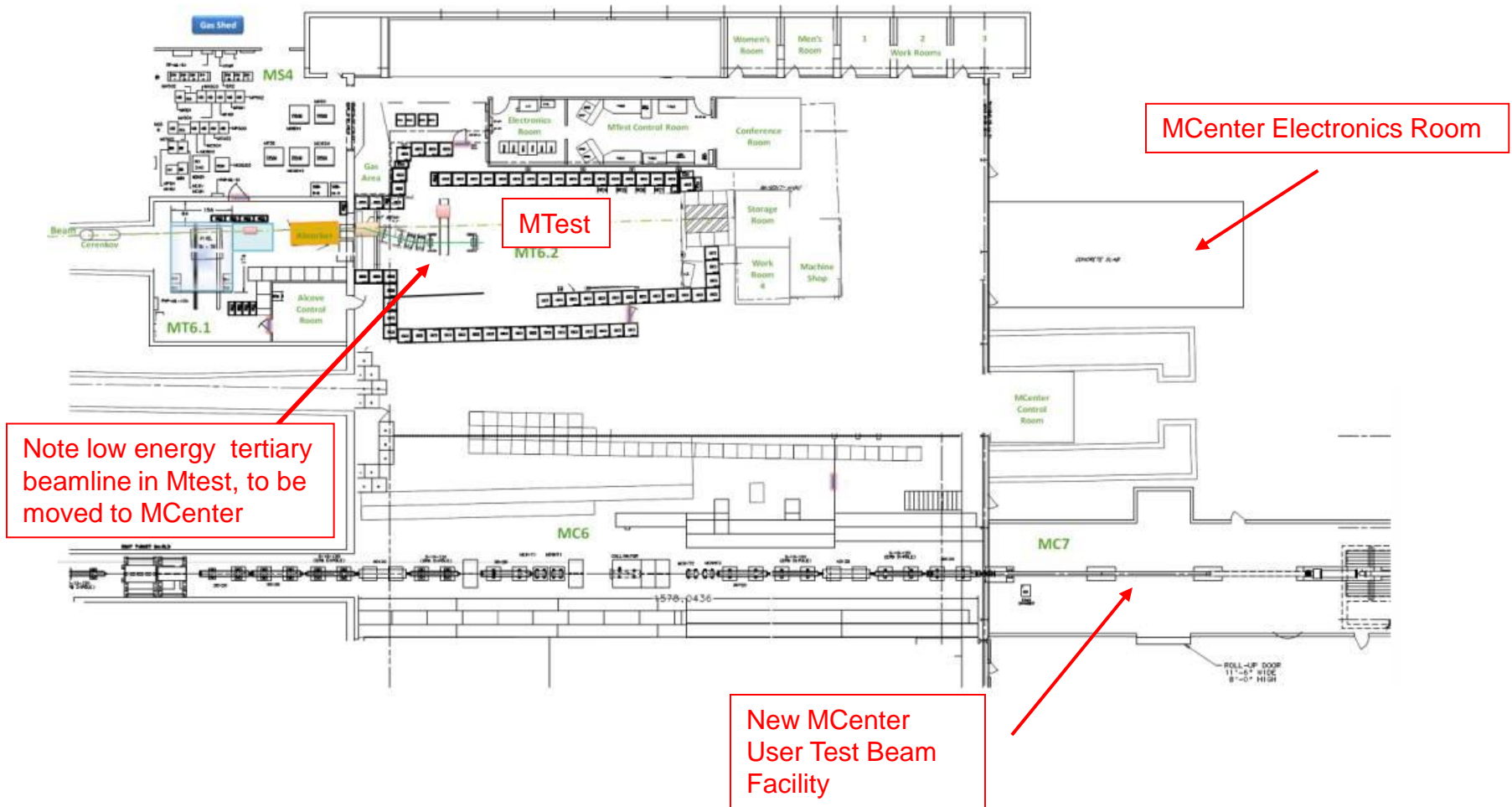
Fermilab MTest Test Beam Facility

- User amenities include:
 - » 3 motion tables
 - » Tagged cable plant for signals and HV
 - » Gas delivery infrastructure
- Beam instrumentation including:
 - » Pixel detector tracking,
 - » Wire chamber tracking,
 - » Time-of-flight,
 - » Calorimetry
 - » Differential Cerenkov



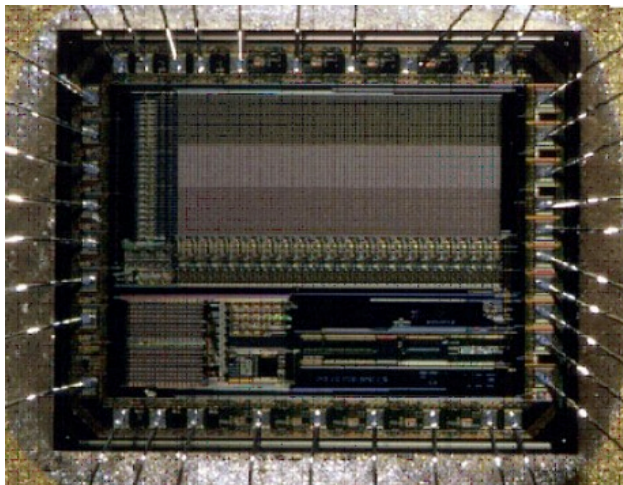
- Tunable secondary beams, with beam composition and energy spread (1-3%) a function of energy.
- 120 GeV proton beam has 7 mm spatial spread, 100 microrad divergence, with rates tunable from 100 Hz to 100,000 Hz

2nd Test Beam - MCenter - coming online this Summer

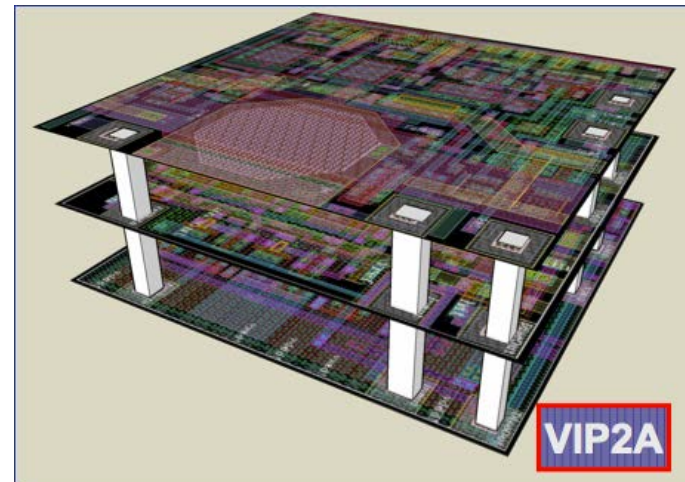


3-Dimensional ASIC Design Program

- Moving information to detector edges will eventually become untenable
 - » Need to explore option of transmitting information vertically
- Fermilab has led the formation of a large international consortium (<http://3dic.fnal.gov>) addressing this technology
- Tools and techniques have been adopted by the major silicon fabrication brokers: MOSIS, CMP and CMC



Conventional Monolithic
Active Pixel Sensor



3 tier 3D stack for FNAL ILC vertex
chip, fabricated by MIT-LL

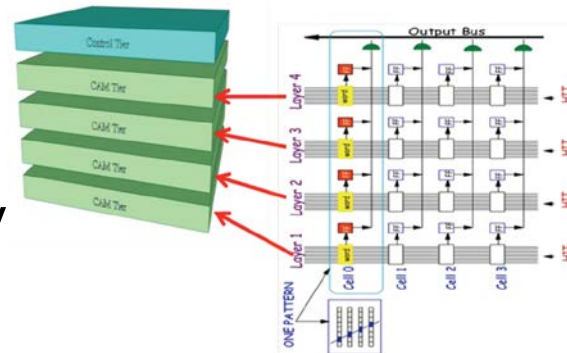
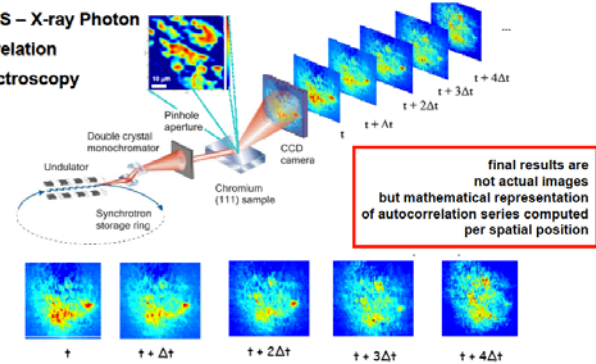
Current Activities in 3D ASICs

- 3D with Tezzaron
 - » VICTR track finder for CMS
 - » VIPIC for LC
 - » VIP for time correlated X-ray detection
- Silicon On Insulator
 - » MAMBO (OKI/KEK) for X-rays
- VICTR II data flow for CMS track trigger
- VIPRAM – 3D associative memory
- CMS Phase II pixel chip
- Mechanical Design
 - » Track trigger module and support
 - » LC supports and design
 - » Power delivery

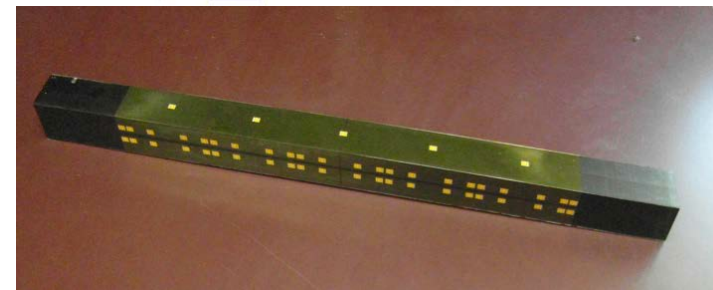
CMS track trigger module box
beam support for carbon fiber
EMI testing

3D Consortium and Fermilab

XPCS – X-ray Photon Correlation Spectroscopy



VIPRAM 3D
CAM Concept
for triggering



The Liquid Argon Program

- Low-cost, low background and highly efficient liquid argon TPC are critical for neutrino and dark matter physics
- Fermilab expanding on existing techniques and test beam efforts (ArgoNEUT)
 - » R&D toward implementing truly large detectors (20-30 kton) with industrial techniques



ArgoNeut TPC field cage and installation in NUMI underground lab. Will be moved to MCenter.



Liquid Argon materials and electronics test stands

Distillation Column for LAr Purification

- CryoEngineering group has collaborated with Princeton to create a distillation apparatus to supply the dark matter community with low- ^{39}Ar obtained from gas wells
 - » More than two orders of magnitude improvement in background levels



A High Power Laser Lab

- Developed in an empty beamline (MEast) to support space-time and dark matter axion research
- Contains a 2 watt laser with cavity finesse of 1000, and thus 2 kW of stored power in a baseline of 40 meters
- Developed PZT controlled cavity mirrors instead of typical spring suspension, to reduce lower frequency (<1 kHz) noise



- Applications for control of high intensity optical beams:
 - » Optical beam dump searches for axions, hidden-sector photons
 - » Precision interferometric position measurements (Holometer)
 - » Precision interferometric angular motion measurements (5th force searches)

Access to Fermilab facilities

- Fermilab web site has useful links to detector organization and facilities, as well as links to the EDIT school and detector retreat: <http://detectors.fnal.gov>
- Useful Emails:
 - » FNAL detector point-of-contact: ramberg@fnal.gov
 - » Detector Advisory Committee: detector-advisory@fnal.gov
 - » Detector R&D mail list (94 members): detectors@fnal.gov
 - » Test beam users (116 members): test_beam@fnal.gov



Facilities at SLAC

- Building 33 detector assembly clean room
 - » Main space is 3500 ft² with an additional 850 ft² of high bay area
 - » Used for GLAST originally, now being modified for LSST camera
- Silicon Detector Laboratory in Building 84
 - » 500 ft² space for assembly & testing of semiconductor devices
 - » Finetech Lambda flip-chip wire bonding machine with 0.5 micron alignment precision
- Electronics and DAQ test lab

SLAC Building 33
Detector Assembly clean room

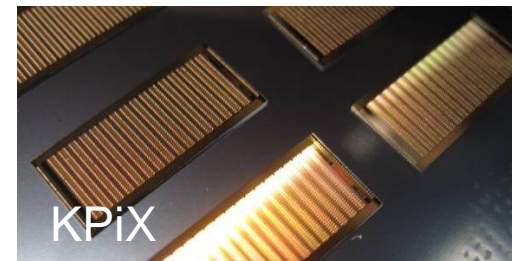
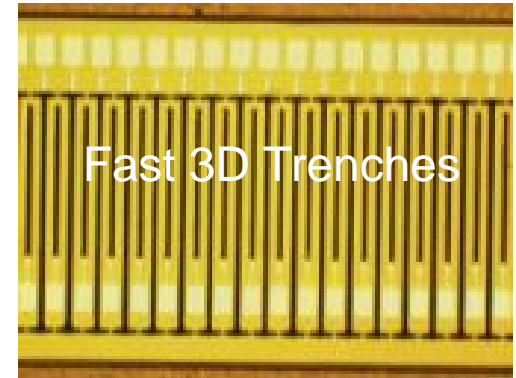


SLAC Building 84
Silicon Detector Laboratory

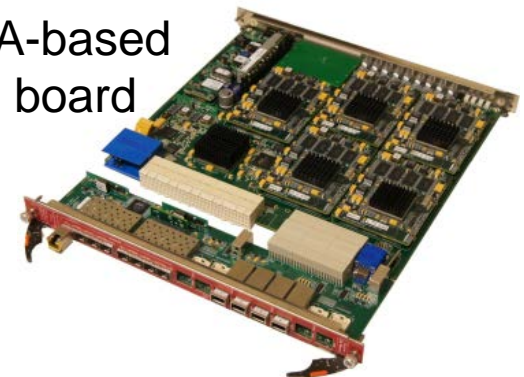


Core engineering capability

- Sensor and integrated electronics development R&D
 - » Sensors for timing, energy, spatial resolution (fabricated at Stanford Nanofabrication Facility)
 - » Ambitious plans for new sensors pushing silicon technology
 - » System-on-a-chip designs, custom ASICs
- Detector systems R&D
 - » High density, low mass, low power front-end systems for calorimetry and tracking
 - » In detector high-speed signal transmission
 - » Low-radioactivity readout electronics
 - » Low-temperature electronics
- DAQ and computing development R&D
 - » High-performance next generation DAQ systems
 - » MDI studies, {detector simulation toolkit, PFA studies} and related tracking & calorimetry

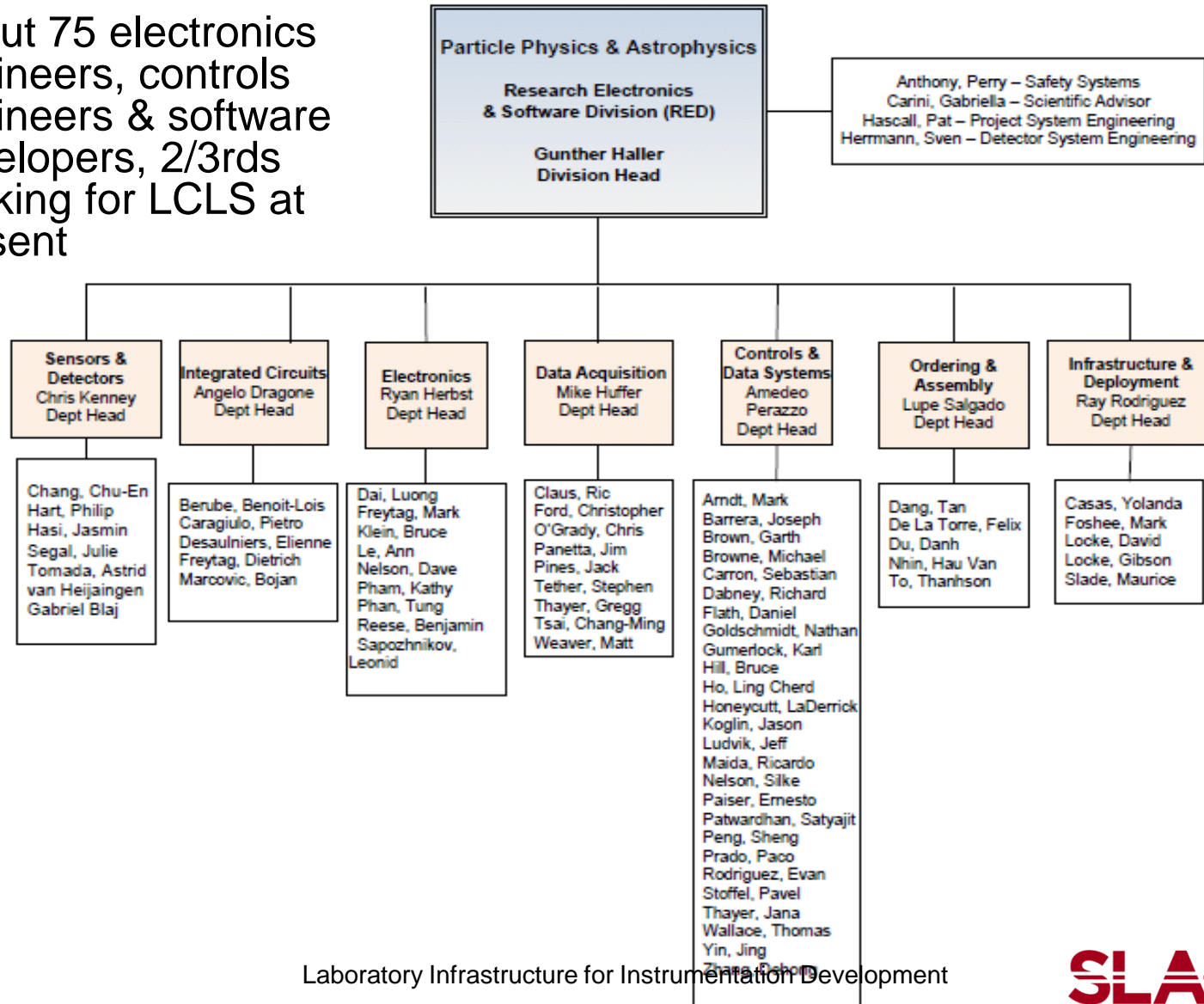


ACTA-based RCE board



Core electronics and software capability

- About 75 electronics engineers, controls engineers & software developers, 2/3rds working for LCLS at present



Sensor processing & characterization facilities

- Access to extensive existing micro and nano-fabrication infrastructure on Stanford campus
 - » SNF has full suite of micro and nano processing equipment: stepper, contact aligners, epitaxy reactors, 10 plasma etchers, 20 furnaces, 6 ALDs, etc
 - » Silicon Valley location facilitates use of services from specialized micro-electronics companies



Stanford Nano-Characterization Lab
TEMs, SEMs, Auger, XPS, XRD, etc.

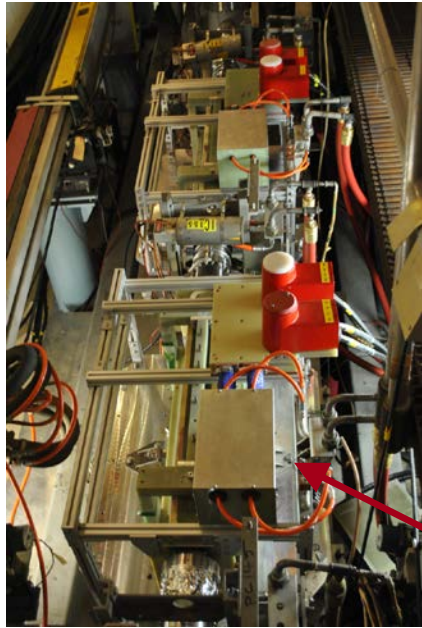


Stanford Nano Center
140,000 ft², TEMs, ion mill,
ebeam litho, etc.



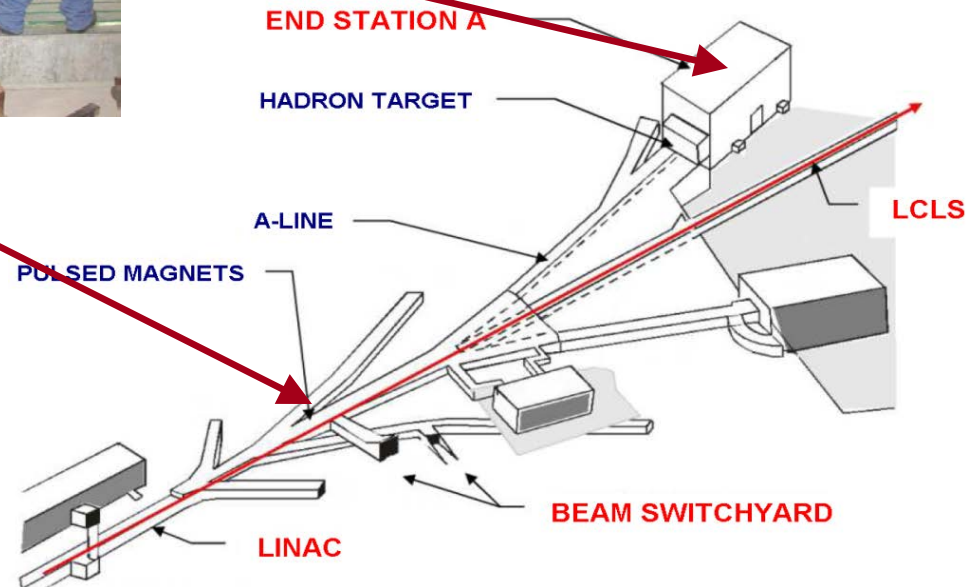
Stanford Nano-Fabrication Facility

End Station Test Beam (ESTB)

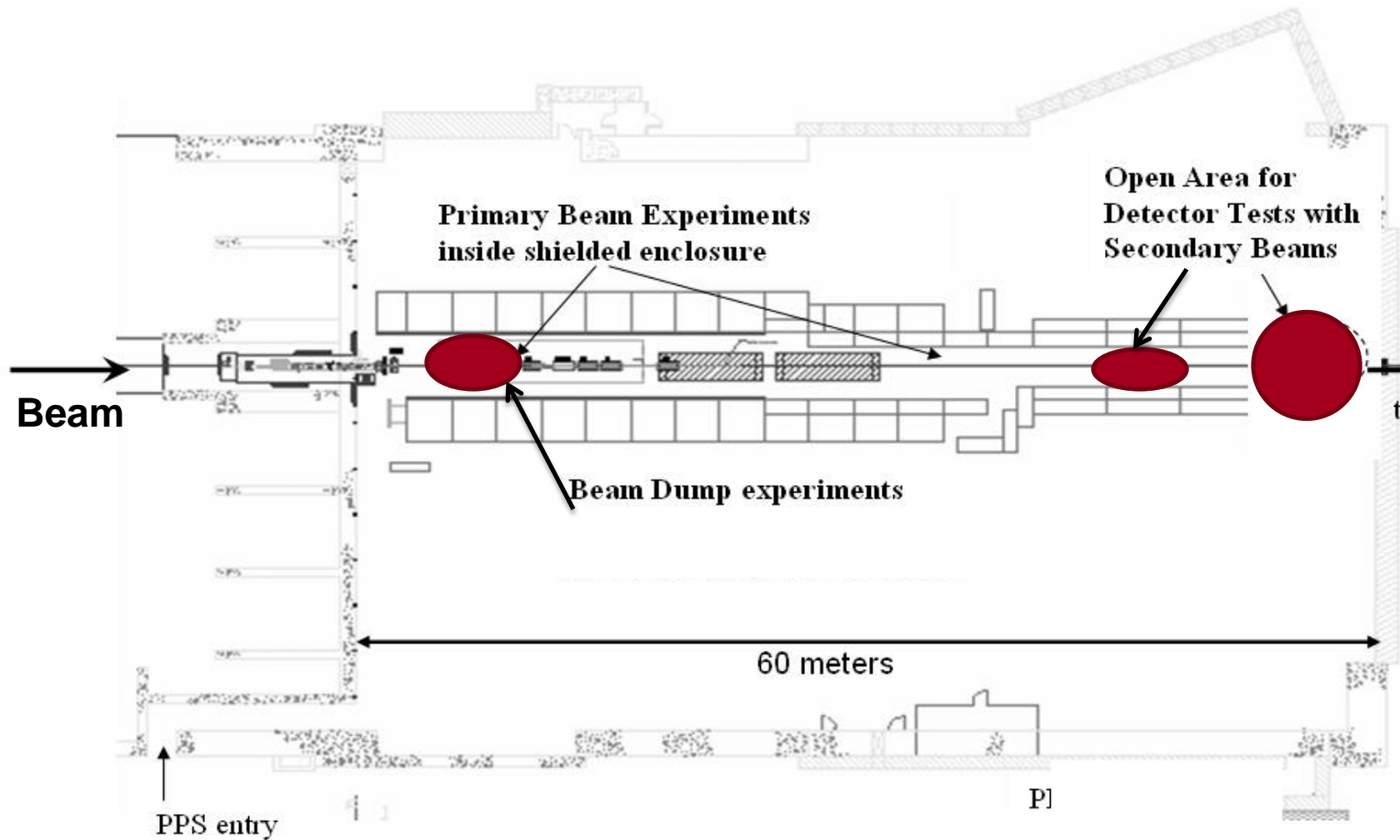


- World's only high-energy primary electron beam for MDI & beam instrumentation
- Exceptionally clean and well-defined primary and secondary electron beams

- Uses pulsed magnets in beam switch yard to parasitically extract LCLS beam to ESA
- First beams extracted March 26 to ESA beam dump

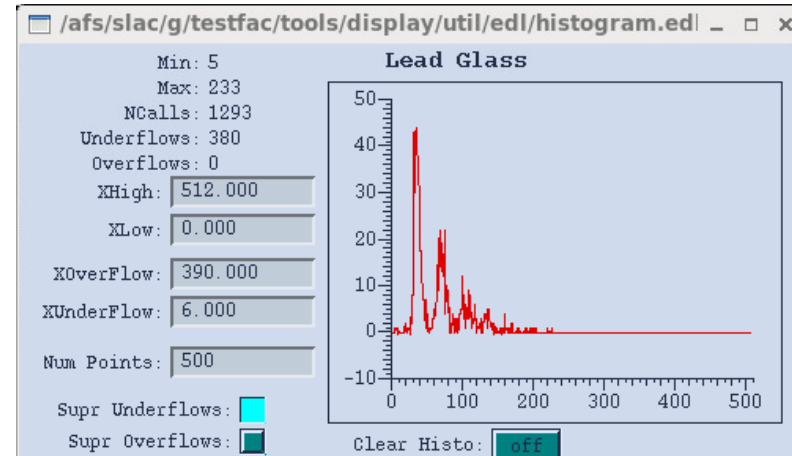


Layout for ESA



LCLS and ESTB Beams

- LCLS beam (min and max parameters)
 - » Energy: 2.2 –15.0 GeV; typical around 5 or 13 GeV
 - » Repetition rate: 120Hz
 - » Beam current: 20 to 250 pC; typical 150pC
 - » Beam availability > 95%!
- ESTB beam
 - » Kick the LCLS beam into ESA @ 5 Hz
 - » Primary beam 2.2 -15.0 GeV
 - Determined by LCLS
 - $<1.5 \times 10^9$ e-/pulse (250 pC)
 - » Clean secondary electrons
 - 2 GeV to 13 GeV, 1 e-/pulse to 109 e-/pulse



Secondary particles on new Cu-target at the PM3 location in the BSY as recorded by a Lead Glass Counter

Users for April to July and beyond

- Approved proposals
 - » T-505: Tests of 3D silicon pixel sensors for ATLAS, P. Grenier, SLAC
 - » T-506: EM Shower Damage to Si Diode Sensors, Bruce Schumm, UCSC
 - » T-507: Test of a RICH-Prototype Based on CsI-GEMs for an Electron-Ion Collider, K. Dehmelt, Stony Brook University
 - » T-508: HERA-B ECal modules beam test in ESTB at SLAC for GEp(5) at Jefferson Lab, E. J. Brash, Christopher Newport University
 - » T-509: Develop a Neutron Beam Line for Calibration of Dark Matter Detectors, J. Va'Vra, SLAC
- Proposals in development
 - » Will receive the ATLAS Silicon Telescope in September for one year
 - Several Atlas R&D proposals in draft form
 - » Performance confirmation of Belle II imaging Time of Propagation prototype counter, G. Varner, Univ. of Hawaii
 - » Calibration of the g-2 calorimeter, D. Hertzog, Univ. of Washington
 - » Test of a Silicon-Tungsten Electromagnetic Calorimeter for the ILC SiD, R. Fry, Univ. of Orgeon
 - » Geosynchrotron radio emission from extensive air showers to detect ultra-high energetic neutrinos at Antarctica, K. Belov, UCLA



Detector R&D coordination among HEP labs

- HEP labs planning to organize a series of small specialized workshops with invited participation
 - » Intent, in part, is to review capabilities, future needs, and move towards reducing duplicated effort where identified
- Tentative list of topics:
 - » ICs and ASICs [LBNL this spring]
 - » Sensors including strips, pixels and CCDs
 - » DAQ and trigger
 - » Noble liquid systems and cryogenic engineering
 - » Low-background detector and materials development, including assay techniques
 - » Specialized mechanical engineering, including low-mass materials and supports



Community access to lab facilities

- DOE generic detector R&D program created in FY2008
 - » Has led to development of coherent organization structures for detector R&D efforts in laboratories
- Laboratories all have points-of-contact designated for community to request access and work with laboratories on new ideas
- Most laboratories moving towards Fermilab model of annual evaluation of opportunities and priorities
- CPAD also has a central role in communicating capabilities and providing community input on priorities and directions

Backup